# Status of High-Granularity ADRIANO2 R&D in T1604

# (Very) Preliminary results of June 2021 test beam

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On behalf of T1604 Collaboration

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# **Rationale for ADRIANO2**

- ADRIANO2 calorimeter
  - High-granularity tile calorimeter for PFA and dual-readout techniques
  - Sandwich of lead-glas and scintillating tiles optically independent
  - On-tile sipm readout
- Fast timing
  - Goal is 80 psec with ASIC readout (Petiroc2)
- Target experiments:
  - EIC and REDTOP (for now)





#### **Tiles for Test Beam**

#### Three sizes

- $3x3x1 \text{ cm}^3$ ,  $3x3x2 \text{ cm}^3$ ,  $3x3x3 \text{ cm}^3$
- Three surface finish
  - Cut ground, sandblasted, polished
- Six coating
  - BaSO4, Teflon, Kevlar, Al sputtering, Al paint, ESR2000
- Two sensor interfaces
  - Dimple, no-dimple
- Two sensors
  - S13360, S14160 (6x6 mm<sup>2</sup>)
- One special tile
  - Two sensors Al painted

#### **Total: 24 tiles tested**

# **Tile preparation**

- Tiles manufactured at Cat-i-glass (US) from SF57 blocks.
- All coating at NIU (thanks to T. Fletcher and M. Figora).
- Sputtering at NIU Chem Dept. (thanks to E. Nesterov)
- Porka boards v2 for FEE (S. Los)
- Sampic and Wavecatcher for DAQ

#### **Polished vs unpolished Tiles**





#### Dimple vs no dimple





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### **Coating vs wrapping**





Ag deposition





PTFE wrapping

## Al/Ag sputtering (NIU Chem. Dept.)



- Angstrom Engineering Nexdep series vacuum thermal deposition system mounted into an Innovative
- Pechnologies-glove<sup>tib</sup>ox (E. Nesterov lab. NIU Chem. Dept.)





#### **Coating coverage test**

#### BaSO4 paint



#### Al sputtering

Sputtering contaminated during tile manipulation in the glove box

# The saga of aluminized wrapping (latest measurements)



spectrophotometer with DRA900 diffusive reflectance chamber (E. Nesterov lab. – NIU Chem. Dept.)

#### • Esr2000 consistently shows above 100% reflectivity

July 16, 2021

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#### **Fluorescence** spectra



- Measurement performed with an PTI QuantaMaster4/2006SE spectrofluorimeter (E. Nesterov lab. – NIU Chem. Dept.)
- The excitation and emission spectra were acquired at the right-angle configuration

#### **Results by M. Janecek are fully confirmed (brilliant fluorescence** with <u>τ</u>=14nsec) July 16, 2021

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#### <sup>90</sup>Sr measurements (A. Dychkant)









#### **FEE + Tiles with dimple**



3D printed tile+FEE holder (M. Figora)

### FEE and DAQ: Test beam

Porka boards with Sampic (6.4 GSa/sec – 64 Sa) and wavecatcher digitizers (3.2 GSa/sec – 1024 Sa)



- FEE and slow control designed at Fermilab (S. Lo
- Integration with FTBF and slow control: K. Francis (NIU) J. Maalmi (ICJlab)

**U58** 65/5 DIGITIZER Trigge Channel I npul

**Sensors+FEE (S. Los)** 

#### S14160: 1 ns rise time S13660: 2.7 ns rise time Vertical Horiz/Acq Irig Display Cursors Measure Masks Math MyScope Utilities Help 08 May 21 15:85:05 47200 Acqs Buttons Edit 05 May 21 18:30:41 Buttons 6000 Acgs Average **Ch1** Position Tek Run 2.0div **Ch1 Scale** 50.0mV 1.044ns all(C1)! 1.0626 Rise(C1)! 287.6ns M 80.0ns 2.5GS/s 40002/0 100mV Ω M 80.0ns 5.0GS/s A Ch1 \ -53.0mV 200ps/pt 50.0mV Ω PDE = 40% at $\lambda p$ PDE = 50% at $\lambda p$ Noise: ~2 MHz Noise: ~10 MHz Gain: 1.7x10<sup>6</sup> Gain: 2.5x10<sup>6</sup> Overvoltages set to have similar signal for 1 pe July 16, 202

#### June 2021 Test beam Setup

#### New FEE boards: similar to the



#### **ADRIANO2 at FTBF**



# **Test beam results – June 2021**

#### **Very preliminary analysis**

Amplitude analysis based on Wavecatcher only
Time analysis based on Sampic and Wavecatcher
Calibration approximate for now; need a new led run

Light yield results finalized after calibration is complete

#### **Noise analysis** Use Sampic at 6.2 GSa/s on baseline of waveform





□Use WC/SAMPIC trigger in single on one channel and acquire the other channels arriving within +-200 nsec

Determine pedestal independently

□Fit the amplitude plot with multiple equi-spaced gaussians + pedestal





With the Tektronix

Preliminary



S14160 - no beam - untriggered - Amplitude [V]

#### **MIP** Amplitude Analysis (Wavecatcher)

Diffuse coating



#### **MIP** Amplitude Analysis (Wavecatcher)

Mirror coating



## Summary LY/MIP Analysis



- 1 MIP in SF57 ~ 9 MeV/cm
- Teflon and BaSO<sub>4</sub> coating have very similar LY
- Kevlar has about 40% lower LY
- BaSO<sub>4</sub> tiles (ground) with dimple & S13360 have about the same LY as no-dimple & S14160 (surprising)
- Teflon tiles (polished) with dimple & S13360 have about 30% lower LY as no-dimple & S14160
- Al-sputtered and Al-paint have 1/3 the LY vs diffuse coating
- 3 cm thick sandblasted, BaSO<sub>4</sub> tile has 15% lower-than-expected LY (real or bad sipm coupling?)

#### Waveform with SAMPIC @ 6.4 GSa/s



#### Waveform with WC @ 3.2 GSa/s



Similar risetime as measured with Sampic

#### $\Delta T$ measurement

# Preliminary Time difference between two waveforms from 2 cells determined with a CF discriminator

Save Histo	Nb of bins inTime Histo	Mean (ns) 0.784 RMS (ps) 277.69	Fitted Mean (ns) 0.000 Sigma (ps) 0.00	FWHM (ps)		<u>i.</u> Time Measuren	nent Histogram Nb of bins inTime Histo	Mean (ns)	Fit
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1937-						2014-			
4663-			-3 -			1914-			
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		Time differen	nce (ns)					Time differen	nce

#### S13360: ΔT=68 ps

Fitted Mean (ns) 0.000

Sigma (ps)

FWHM (ps)

157.29

50 0.500 0.750 1.000 1.250 1.500 1.750 1.985

#### $\Delta T$ measurement

×

1.750 1.985

# Preliminary Time difference between two waveforms from 2 cells determined with a CF discriminator

Save Histo	Nb of bins inTime Histo	Mean (ns)         Fitted Mean (ns)           1.225         0.000           RMS (ps)         Sigma (ps)           9232.54         0.00	FWHM (ps) 276.46	Save Histo	Nb of bins inTime Histo ↓ 100 Nb Of Entries ↓ 5590	Mean (ns) 0.522 RMS (ps) 320.01	Fitted Mean (ns) 0.000 Sigma (ps) 0.00	<b>FWHM (ps)</b> 295.62
397 - 382 - 366 - 351 - 336 - 290 - 275 - 90 - 275 - 90 - 275 - 122 - 199 - 199 - 199 - 199 - 199 - 199 - 122 - 107 - 92 - 107 - 107 - 92 - 107 - 107 - 92 - 107 - 107 - 92 - 107 -	Time diff           2	erence distribution		397- 382- 366- 351- 336- 321- 305- 290- 275- <b>u</b> 260- 275- <b>u</b> 244- 299- 275- <b>u</b> 244- 199- 199- 199- 199- 137- 122- 107- 92- 76- 61- 46- 31- 15- 0- 0-15-	Time diff           2000         <	erence distri	bution	

# Summary

We had a good (but very intense) run in June. Thank you to all who participated to shifts (from KU and NIU), S. L. for setting the electronics, M. F. and T. F. for (dis)installation

All equipment worked flawlessly: Sampic and Wavecathers (ICJ Lab) are superb tools for this kind of R&D

Data analysis is still very preliminary. However, the picure is quite clear:

1.Diffuse coating has excellent LY (exceeding the goal of  $5\%/\sqrt{E}$ ) but poor timing resolution (~100 ps)

2.Mirror surface meet the goal defined in the DOE proposal (50 ps), but has a ~1/3 the LY of diffuse coatings. Poor sputtering, makes this measurement inconclusive

3.ESR2000 confirmed a large and very slow fluorescence component  $\rightarrow$  drop it from future R&D

# **Future prospects**

Need to confirm the performance of mirroring surface with good sputtered tiles

- Reasons for mirror coating being faster than diffuse coating not understood yet. If it is related to the directional property of Cerenkov photons, need to test at different impinging angles
- FNAL has the expertise and the equipment for good quality sputtering. Very expensive process (\$ 25K). Working with PPD to get support
- Plans are to run again in Fall 2021 with 12 new tiles with Al and Ag sputter
- Test beam with large prototype (32-64 ch) with Petiroc2 readout still on track for Winter 2022

# **Backup Slides**

### **Foreseable Applications**



#### EIC (Photon Project)

